

Octane Elite EDS System

Specifications – EDS



- Highest resolution with premium resolution option
- Increased light element sensitivity
- Outstanding low-energy performance
- Silicon nitride window
- Suitable for plasma cleaning
- High-speed data processing
- Market-leading throughput count rate
- Integrated EDS-EBSD-WDS option with Trident Analysis System

Product	Octane Elite EDS System
Detector	Silicon drift detector
Technique	EDS
System resolution (eV)	125, 123 @ Mn K α @ 10k cps
Detector module	Vacuum encapsulated
Slide	Motorized
Chip size	Plus – 30 mm ² Super – 70 mm ²
Window material	Silicon nitride (Si ₃ N ₄)
Window thickness	<100 nm
Cooling system	Peltier
Throughput	>850k output cps at 2.0m input cps
Peak-to-background	10,000:1
Resolution stability	>90% up to 200k cps
Spectrum display	10 eV/ch
System operating voltage	100 – 240 VAC 47 – 63 Hz
Operating conditions	5 – 35 °C 20 – 80% RH non-condensing